

Advanced Optical Detection through the Use of a Deformably Transferred Nanofilm

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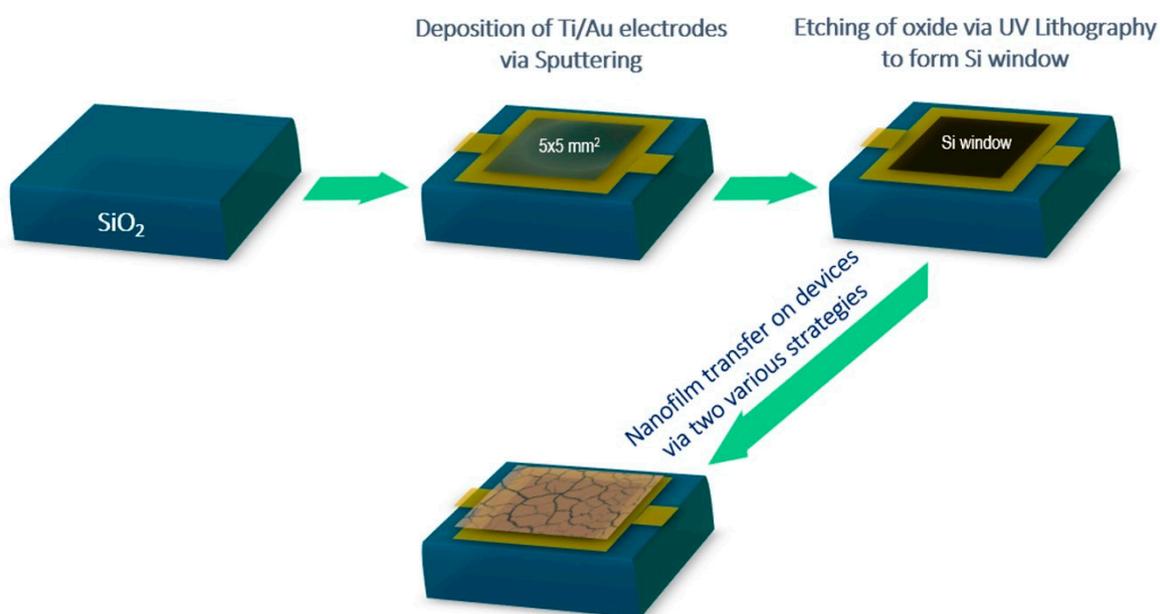


Figure S1. Fabrication process of nanofilm-based photodetection devices.

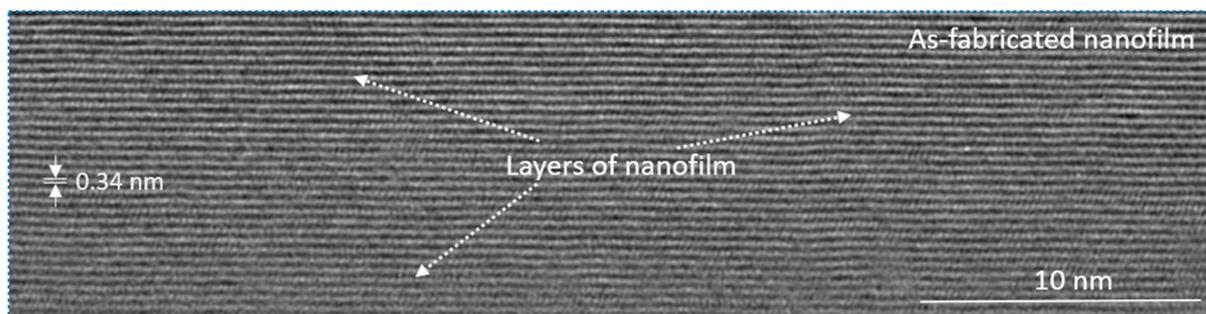


Figure S2. Cross-sectional TEM image of as-fabricated nanofilm.

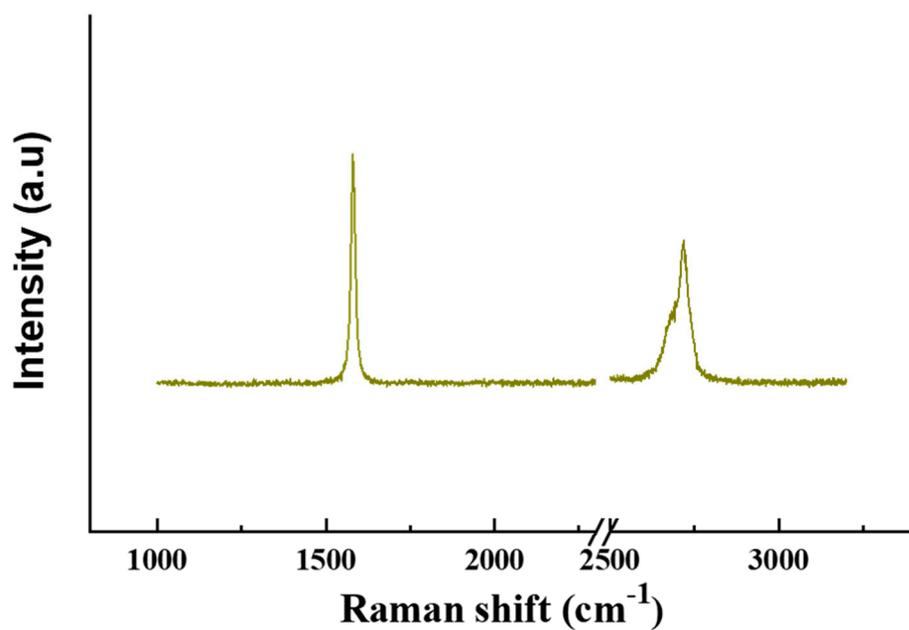


Figure S3. Raman spectra of as-fabricated nanofilm.

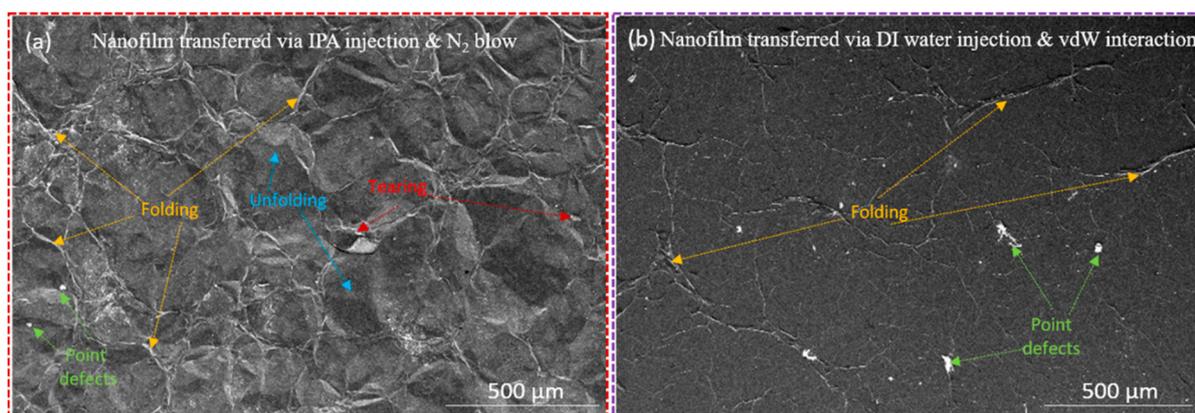


Figure S4. SEM images of nanofilm transferred on Si window via (a) IPA injection & N₂ blow (deformable surface) and (b) DI water injection & vdW interaction (smooth surface).

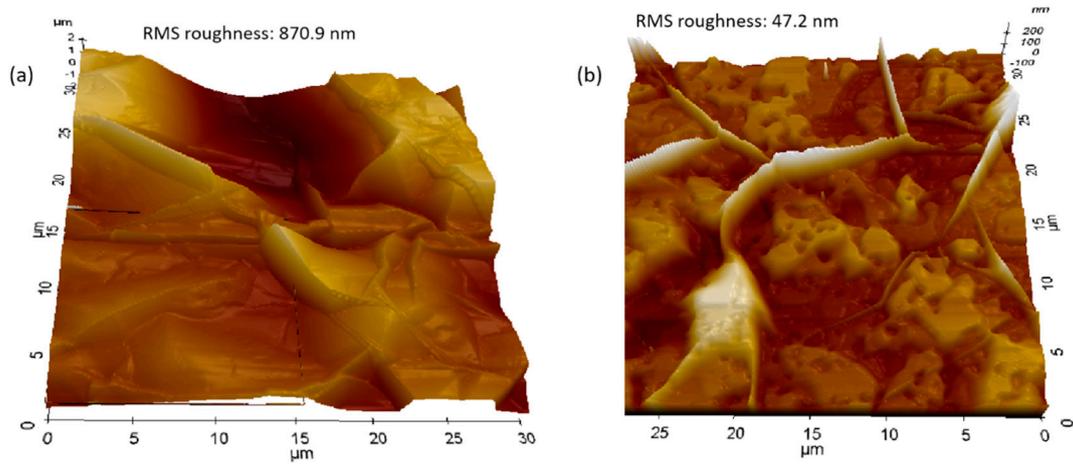


Figure S5. 3D AFM images of nanofilm-transferred on Si via (a) IPA injection & N₂ blow (deformable surface) and (b) DI water injection & vdW interaction (smooth surface).

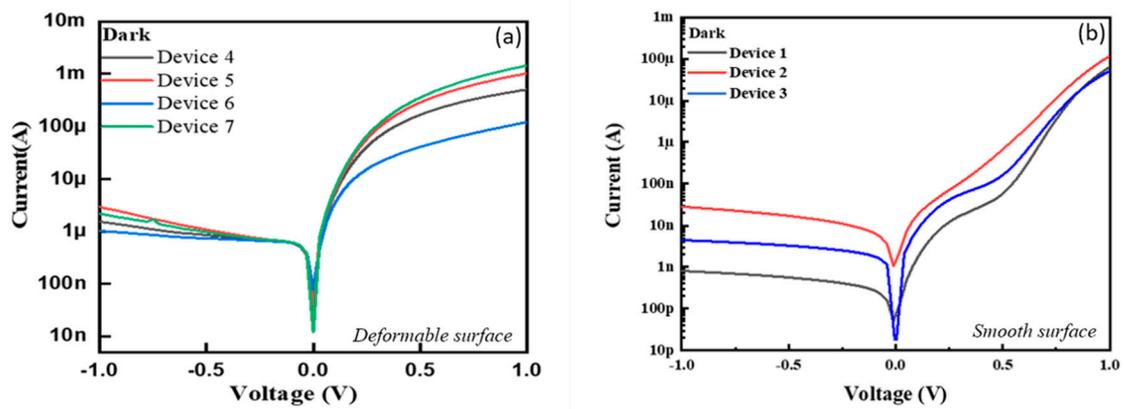


Figure S6. Dark currents measured on various nanofilm-based photodetection devices for two transfer methods via (a) IPA injection & N₂ blow (deformable surface) and (b) DI water injection & vdW interaction (smooth surface).